

1. Record Nr.	UNINA9911006668003321
Titolo	Handbook of contamination control in microelectronics : principles, applications, and technology / / edited by Donald L. Tolliver
Pubbl/distr/stampa	Park Ridge, N.J., U.S.A., : Noyes Publications, c1988
ISBN	1-282-00261-9 9786612002618 0-8155-1745-9
Descrizione fisica	1 online resource (510 p.)
Collana	Materials science and process technology series
Altri autori (Persone)	TolliverDonald L
Disciplina	621.381/73
Soggetti	Integrated circuits - Design and construction Contamination (Technology)
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Nota di bibliografia	Includes bibliographies and index.
Sommario/riassunto	This second edition, edited by the world-renowned Dr. Rointain Bunshah, is an extensive update of the many improvements in deposition technologies, mechanisms, and applications. Considerably more material was added in Plasma Assisted Vapor Deposition processes, as well as Metallurgical Coating Applications.